

ABSTRACT OF THE DISCLOSURE

Self-contained semiconductor device manufacturing equipment has a small floor area so that it can be installed in limited space in a production line, and is highly functional so as to enhance the productivity of the line. The equipment has a plurality of working chambers arrayed in at least a vertical direction, a transfer chamber to which the working chambers are independently connected, and a robot disposed in the transfer chamber for positioning a wafer relative to and transferring the wafer between respective ones the working chambers.